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(12) **United States Design Patent**
Yoshida et al.

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(54) **BOAT FOR SUBSTRATE PROCESSING APPARATUS**

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(71) Applicant: **Hitachi Kokusai Electric Inc.**, Tokyo (JP)

(72) Inventors: **Hidenari Yoshida**, Toyama (JP);
Tomoshi Taniyama, Toyama (JP)

(73) Assignee: **HITACHI KOKUSAI ELECTRIC INC.**, Tokyo (JP)

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(52) **U.S. Cl.**
USPC **D13/182**

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156/345.53, 345.55; 414/217, 220.01, 935,
414/936-941
CPC C23C 16/458; C23C 16/4581; C23C
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C23C 16/4586; C23C 16/4587; C23C
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See application file for complete search history.

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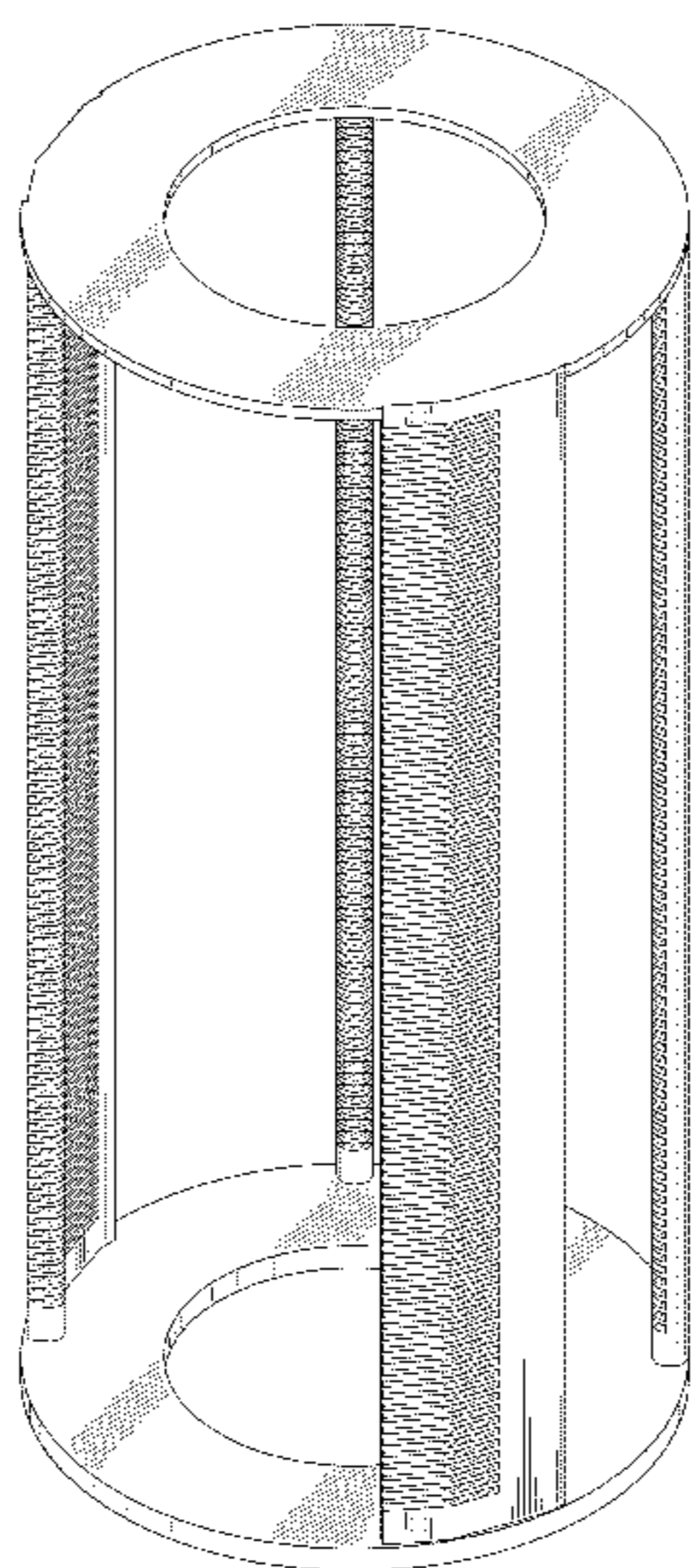
Primary Examiner — Elizabeth J Oswecki
(74) *Attorney, Agent, or Firm* — Fitch, Even, Tabin and Flannery LLP

(57) **CLAIM**
The ornamental design for a boat for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. 1 is a front, top and right side perspective view of a boat for substrate processing apparatus showing our new design; FIG. 2 is a front elevational view thereof; FIG. 3 is a rear elevational view thereof; FIG. 4 is a left side elevational view thereof; FIG. 5 is a right side elevational view thereof; FIG. 6 is a top plan view thereof; FIG. 7 is a bottom plan view thereof; FIG. 8 is a cross sectional view taken along line 8-8 in FIG. 2; and, FIG. 9 is a cross sectional view taken along line 9-9 in FIG. 2.

1 Claim, 8 Drawing Sheets



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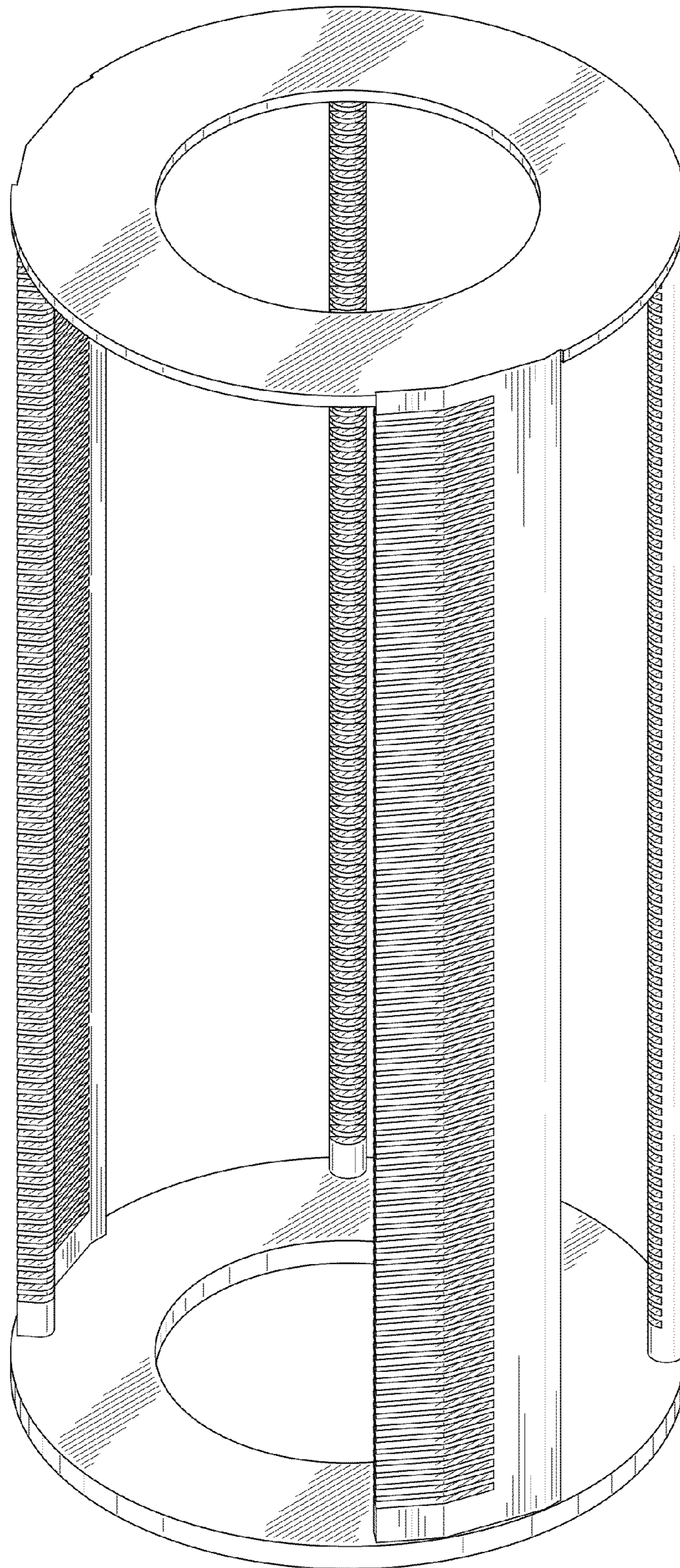
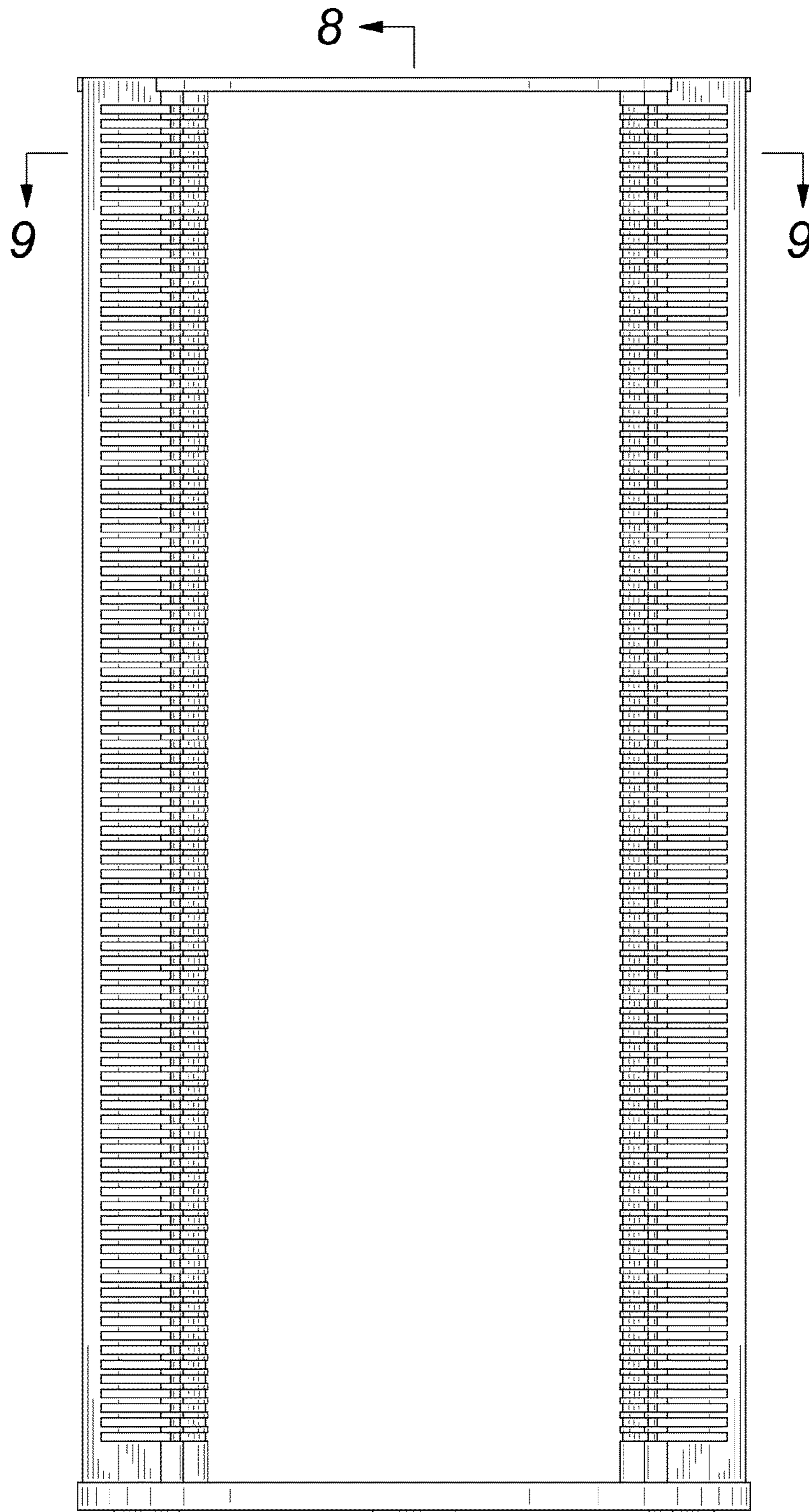


FIG. 1



8 ←
FIG. 2

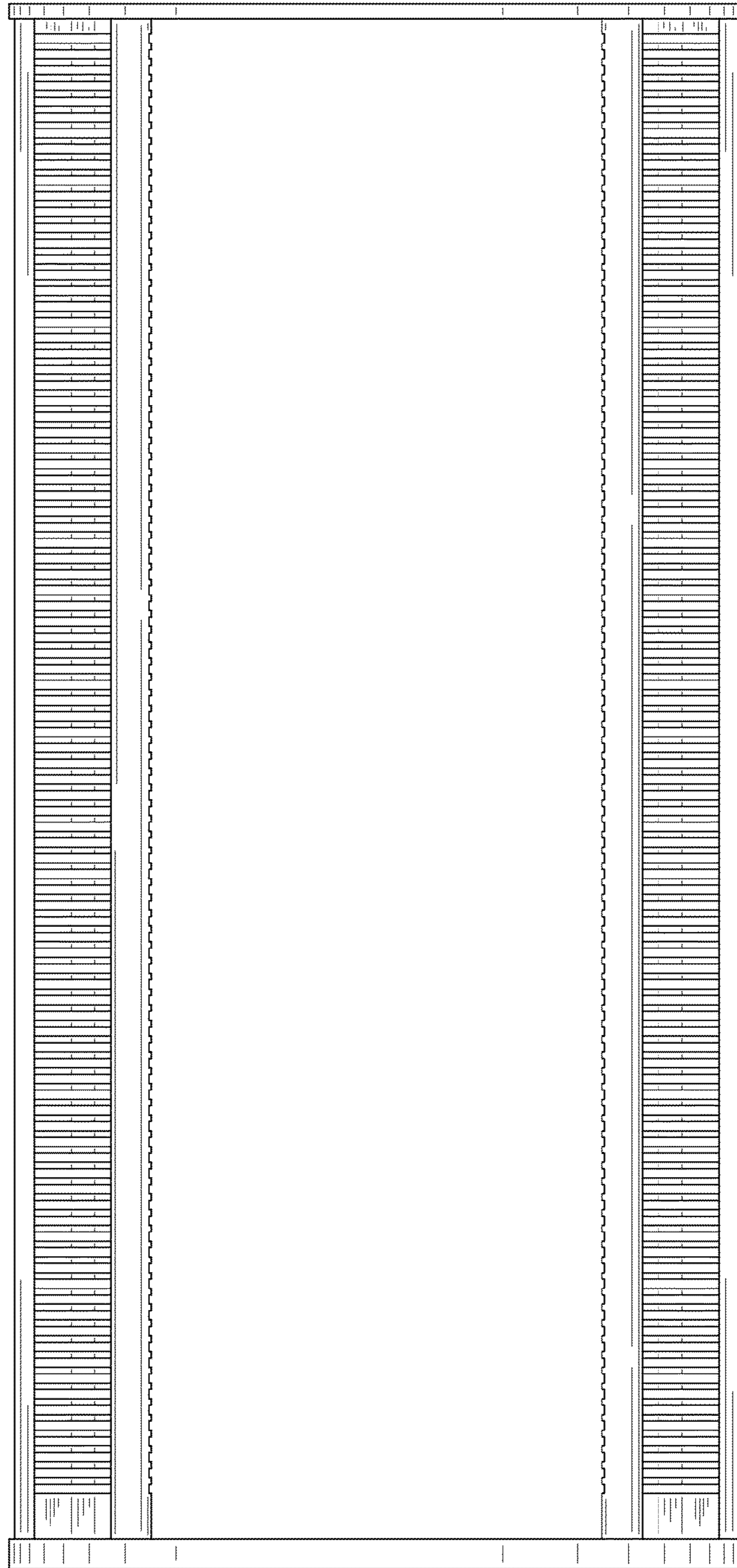


FIG. 3

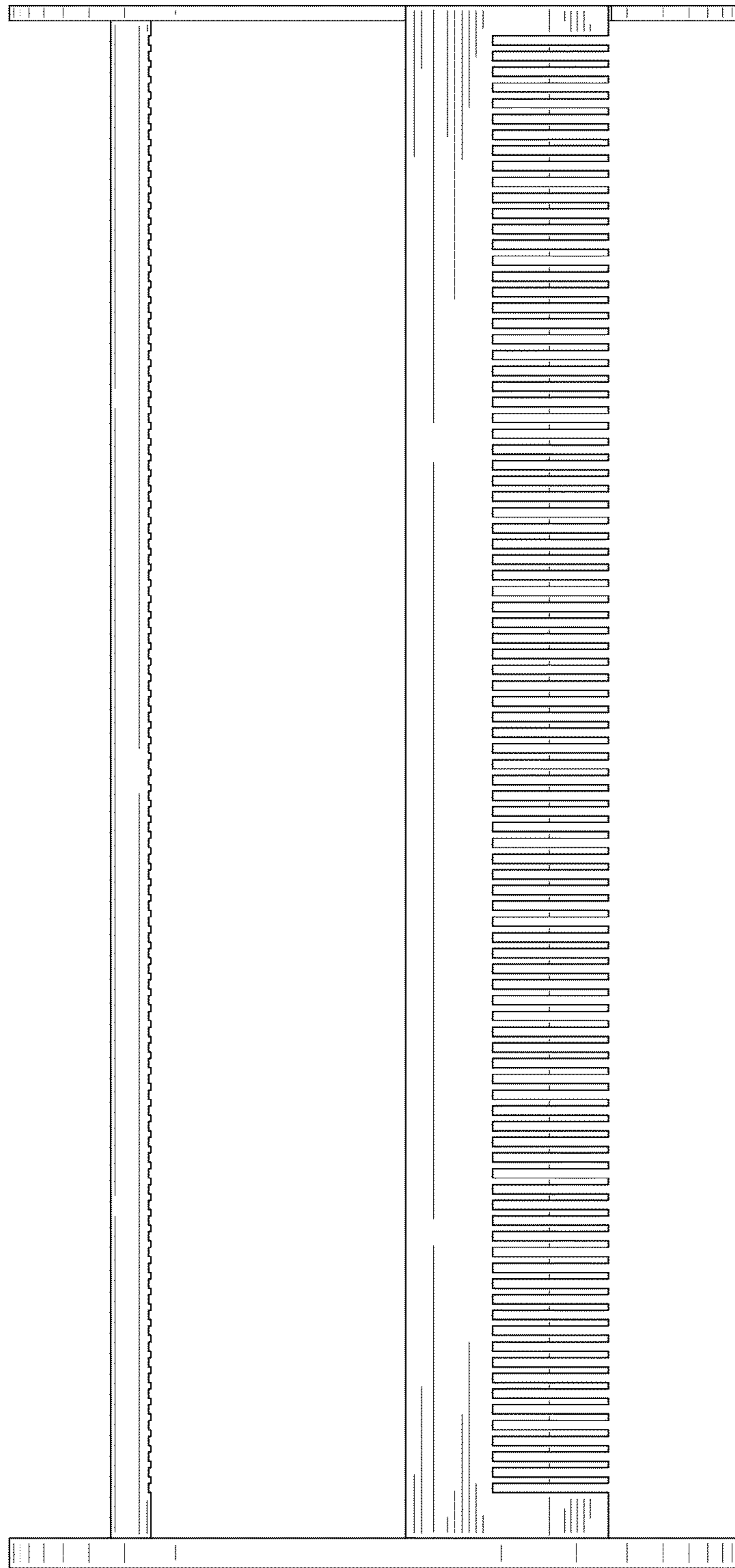


FIG. 4

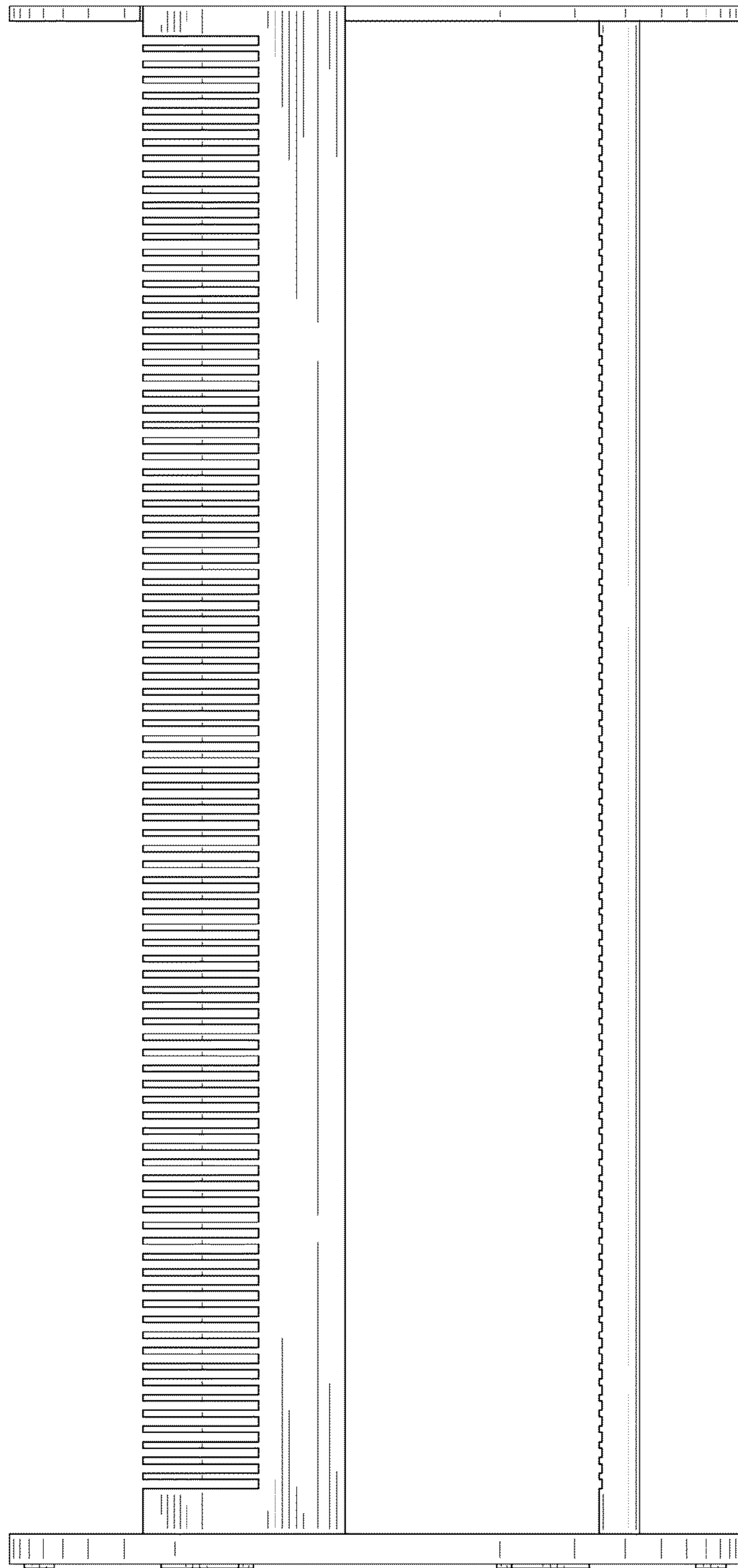


FIG. 5

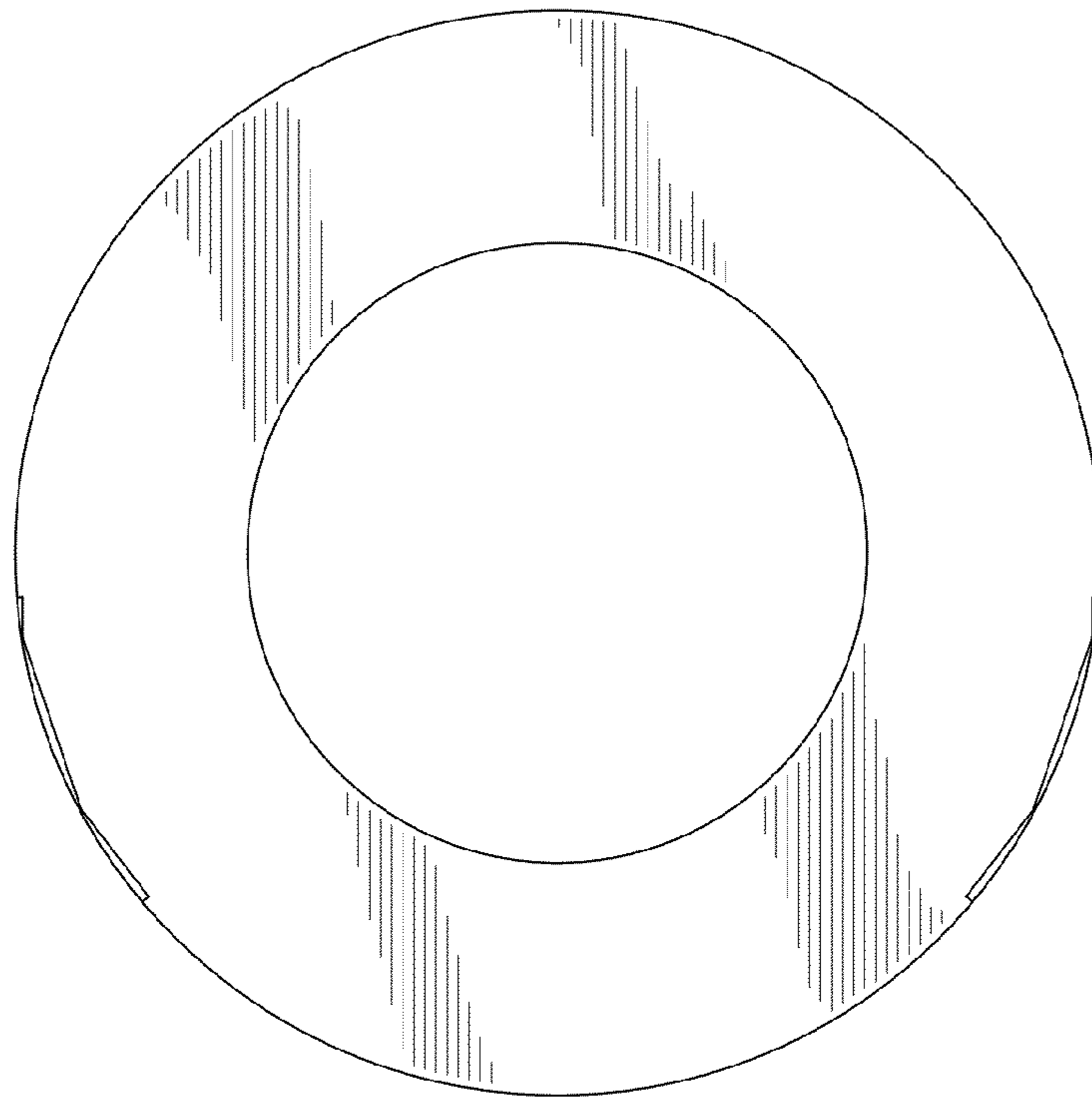


FIG. 6

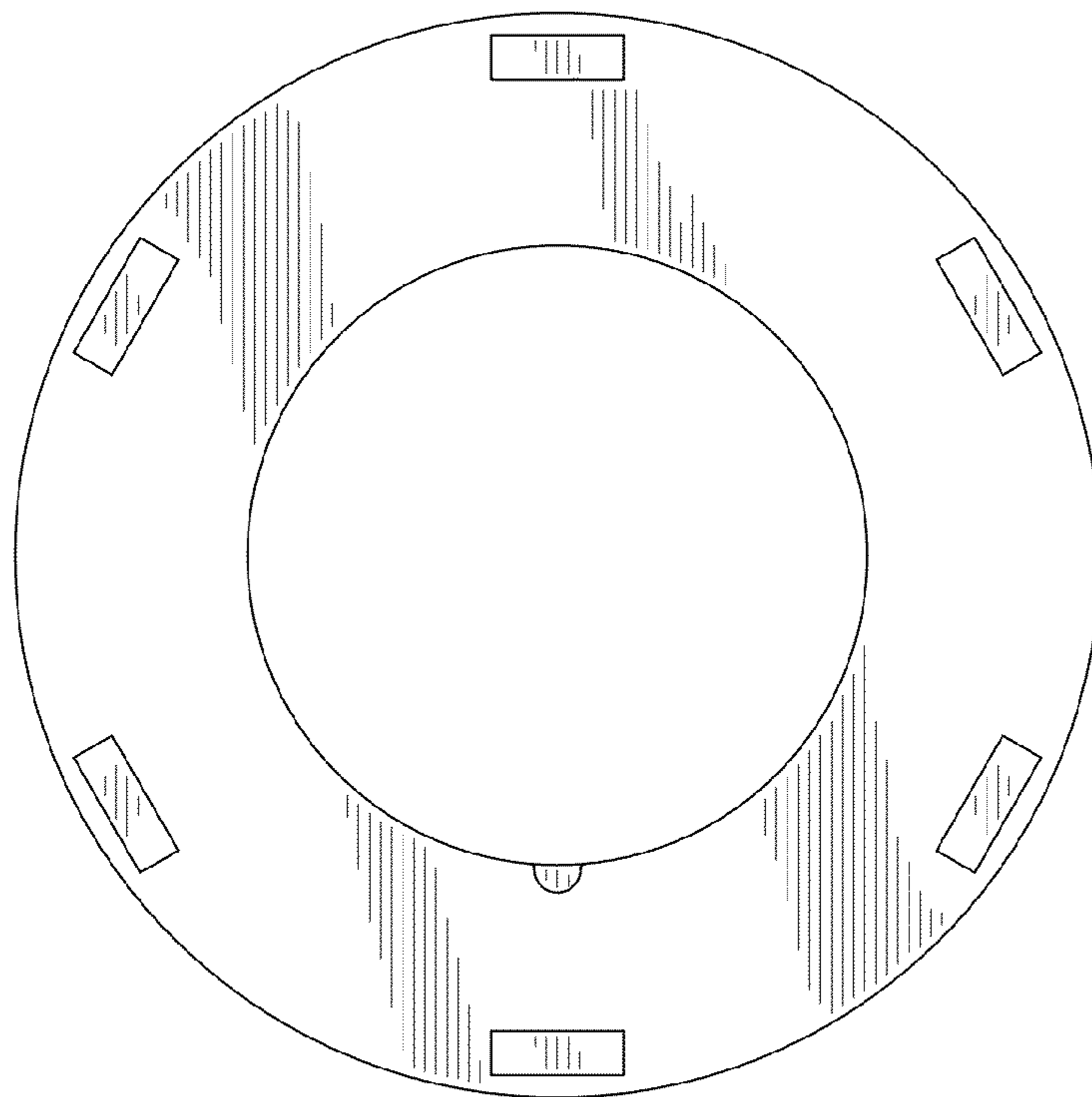


FIG. 7

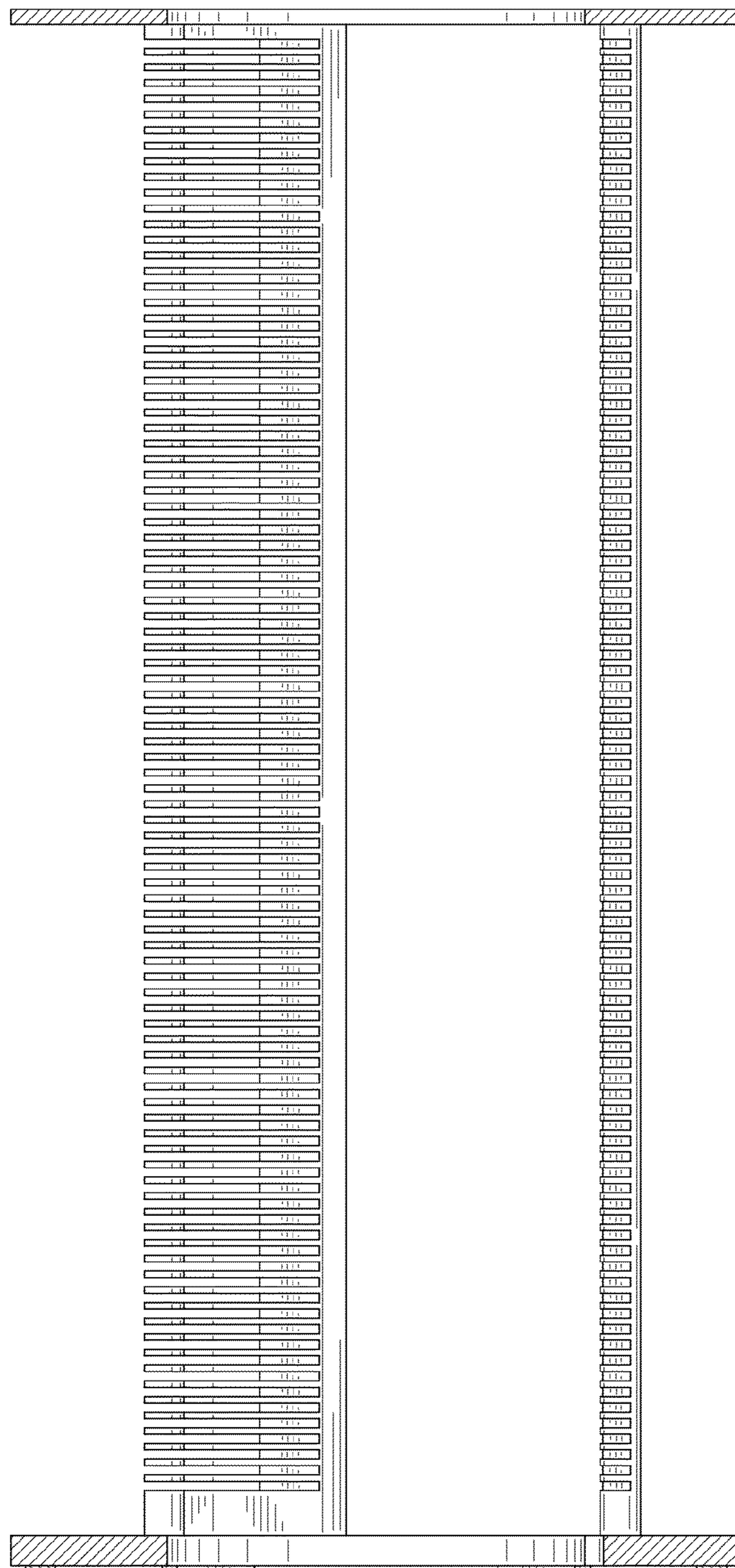


FIG. 8

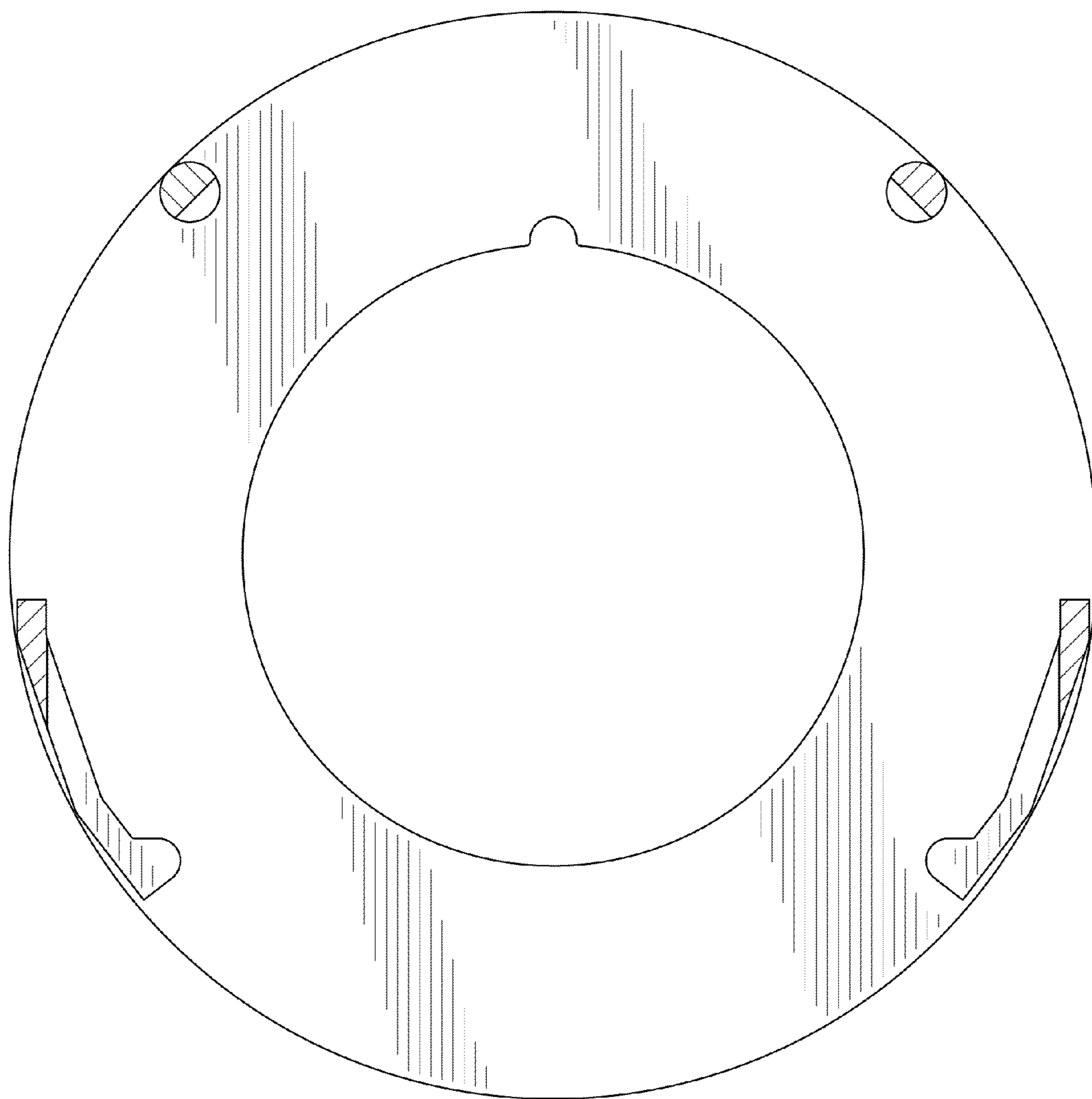


FIG. 9